

IR INSPECTION SYSTEM AND METHOD THEREFOR

ABSTRACT

The present invention provides an IR inspection system for inspecting diced wafer held
5 on a holding tape, comprises an IR imaging device; a liquid pool disposed below the IR
imaging device; and a rotatable table for holding diced wafer adhered on a holding tape,
wherein the rotatable table coupled with a ring wall forming the liquid pool with the
holding tape submerged therein. Operationally, the IR imaging device inspect the diced
wafer through the holding tape having a layer of liquid covered thereon. A method therefor
10 is also provided.

FIG. 1